

applications is corrected to read March 24, 1995.

FOR FURTHER INFORMATION, CONTACT:
Demetrice Jenkins at (214) 767-8001.

11.801 Native American Program
(Catalog of Federal Domestic Assistance)
Dated: March 3, 1995.

Donald L. Powers,

*Federal Register Liaison Officer, Minority
Business Development Agency.*

[FR Doc. 95-5679 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-21-P

Native American Business Development Center Applications: New Mexico

AGENCY: Minority Business
Development Agency, Commerce.

ACTION: Correction.

SUMMARY: On page 9665, in the issue dated February 21, 1995, third column, second paragraph, the closing date for applications is corrected to read March 24, 1995.

FOR FURTHER INFORMATION, CONTACT:
Demetrice Jenkins at (214) 767-8001.

11.801 Native American Program
(Catalog of Federal Domestic Assistance)
Dated: March 3, 1995.

Donald L. Powers,

*Federal Register Liaison Officer, Minority
Business Development Agency.*

[FR Doc. 95-5678 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-21-P

Native American Business Development Center Applications: Oklahoma

AGENCY: Minority Business
Development Agency, Commerce.

ACTION: Correction.

SUMMARY: On page 9668, second column, first paragraph, the closing date for applications is corrected to read March 24, 1995.

FOR FURTHER INFORMATION, CONTACT:
Demetrice Jenkins at (214) 767-8001.

11.801 Native American Program
(Catalog of Federal Domestic Assistance)
Dated: March 3, 1995.

Donald L. Powers,

*Federal Register Liaison Officer, Minority
Business Development Agency.*

[FR Doc. 95-5680 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-21-P

National Institute of Standards and Technology

Announcement of an Opportunity To Join a Cooperative Research and Development Consortium for Alternative Approaches to Nanometer- Level Overlay and CD Metrology for IC Manufacturing

AGENCY: National Institute of Standards
and Technology, Commerce.

ACTION: Notice of public meeting and
notice of Government owned invention
available for licensing.

SUMMARY: The National Institute of
Standards and Technology (NIST)
invites interested parties to attend a
meeting on April 26, 1995 to discuss the
possibility of setting up a cooperative
research consortium to develop
innovative approaches to overlay and
CD metrology consistent with SIA-
projected requirements. Parties
interested in participating in the
consortium should be prepared to invest
adequate resources in the collaboration
and be firmly committed to the goal of
developing innovative approaches.

The program will be within the scope
and confines of The Federal Technology
Transfer Act of 1986 (Public Law 99-
502, 15 U.S.C. 3710a), which provides
Federal laboratories including NIST,
with the authority to enter into
cooperative research agreements with
qualified parties. Under this law, NIST
may contribute personnel, equipment
and facilities—but no funds—to the
cooperative research program.

Members will be expected to make a
contribution to the consortium's efforts
in the form of materials, equipment,
personnel, and/or funds. The program is
expected to last 18 months. This is not
a grant program.

DATES: Interested parties should contact
NIST to confirm their interest at the
address, telephone number or FAX
number shown below no later than
April 7, 1995.

ADDRESSES: Technology Building, Room
B360, National Institute of Standards
and Technology, Gaithersburg, MD
20899.

FOR FURTHER INFORMATION CONTACT:
Michael W. Cresswell, Telephone: 301-
975-2072; FAX: 301-948-4081.

SUPPLEMENTARY INFORMATION: The
National Institute of Standards and
Technology (NIST) invites interested
parties to participate in a cooperative
research consortium to conduct
modeling of overlay detection by
electrostatic/magnetic sensors
interacting with optical metrology target
architectures commonly used in

advanced IC manufacturing, examine
enhancements deriving from target-
geometry modifications and sensor-head
innovations, design and evaluate a test
implementation using Maxwell-
equation-based simulation software and,
formulate specifications of a candidate
design for selected applications.

In conjunction with the opportunity
to join this Cooperative Research and
Development Consortium, the following
invention is available for licensing:

NIST Docket No. 94-040CIP

Title: Method and Reference
Standards for Measuring Overlay in
Multilayer Structures, and for
Calibrating Imaging Equipment as Used
in Semiconductor Manufacture.

Description: Imaging instruments for
overlay-measurement extraction from
partially-processed semiconductor
wafers, are calibrated by providing a
reference test structure having features
which can be located by electrical
measurements not subject to tool-
induced shift and water-induced shift
experienced by the imaging instrument.
The reference test structure is first
qualified using electrical measurements,
and is then used to provided the effect
of the said shifts on the imaging-
instrument measurements.

Dated: March 1, 1995.

Samuel Kramer,

Associate Director.

[FR Doc. 95-5662 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-13-M

Patent and Trademark Office

National Information Infrastructure (NII) Copyright Awareness Campaign

AGENCY: Patent and Trademark Office,
Commerce.

ACTION: Notice of meeting.

SUMMARY: The Working Group on
Intellectual Property Rights of the White
House Information Infrastructure Task
Force (IITF) issued a preliminary draft
of its report, "Intellectual Property and
the National Information
Infrastructure," on July 7, 1994. One of
the Working Group's findings
announced in the preliminary draft is
that effective education of the public
about intellectual property rights is
crucial to the successful development of
the NII. The Working Group recognizes
that the public's awareness of their own
intellectual property rights, as well as
those of others, will lead to increased
respect for those rights.

In order to effectuate public
awareness of copyright, the preliminary
draft, on page 140, stated that the